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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **OZAKI, Takashi, et al.**

Group Art Unit: **2812**

Serial No.: **10/517,765**

Examiner: **Not assigned**

Filed: **February 3, 2006**

P.T.O. Confirmation No.: **6791**

FOR: **SUBSTRATE TREATING APPARATUS AND METHOD FOR  
MANUFACTURING SEMICONDUCTOR DEVICE**

**REQUEST FOR STATUS**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Date: September 1, 2006

Sir:

The undersigned attorney requests the status of the above-identified application.

The application was filed on **February 3, 2006**, in the U.S. Patent and Trademark Office and to date no Office Action has been received.

In the event any fees are required in connection with this paper, please charge Deposit Account No. 01-2340.

Respectfully submitted,

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